

Electrical characterization of TiSi_2 nanocrystals grown on multi-stacked tunnel layer for non-volatile memory

Seung Jong Han¹, Dong Uk Lee¹, Ki Bong Seo¹, Eun Kyu Kim^{1*}, Jun-Seok Oh²
and Won-Ju Cho²

¹Department of Physics, Hanyang University

²Department of Electronic Materials Engineering, Kwangwoon University

The nano-floating gate memory (NFGM) based on nanocrystals (NCs) is a very attractive candidate for non-volatile memory application. The NFGM devices have a small operating voltage, long retention property, and fast program/erase speed. Despite these advantages, the NFGM devices have a problem of trade-off between program/erase efficiency and retention characteristics. Such problem can be improved using high-work function NCs and various tunneling layer.

In this study, we fabricated and characterized TiSi_2 nanocrystal non-volatile memory device with the barrier engineered tunnel layer. The TiSi_2 nanocrystal memory was fabricated on p-type Si (100) wafers. After cleaning wafers, the phosphorus in-situ doped poly-Si layer with a thickness of 100 nm was deposited on isolated active region to confine source and drain. And, the gate regions with the barrier engineered multi-stack tunnel layers were defined on Si substrates by using reactive ion etching. The 5-nm-thick TiSi_2 layer and the 30-nm-thick SiO_2 control layer were deposited on the multi-stacked tunnel layer by using magnetron sputtering. Then, the single layered TiSi_2 nanocrystals were created between the SiO_2 control layer and tunnel layer after post-thermal annealing at 800 °C for 2 min. The aluminum gate electrode of 200-nm-thickness was evaporated by using thermal evaporator. Finally, the photo-lithography and etching processes were carried out for defining of source-drain regions. The channel length and width of the transistor are the ranges of 2 - 10 μm . The electrical properties of devices were measured by using a HP-4156A semiconductor parameter analyzer. Also, the morphology of the TiSi_2 nanocrystals was analyzed by a transmission electron microscope.